



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

2 Application Serial No. 09/298,160
3 Filing Date April 22, 1999
4 Inventor Dan G. Custer et al.
5 Assignee Micron Technology, Inc.
6 Group Art Unit 1746
7 Examiner A. Olsen
8 Attorney's Docket No. MI22-1172
9 Title: Polishing Systems, Methods of Polishing Substrates, and Methods of Preparing
10 Liquids for Semiconductor Fabrication Processes
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13

RESPONSE TO 09/27/2000 OFFICE ACTION

8 To: Assistant Commissioner for Patents
9 Washington, D.C. 20231

10 From: Bernard Berman (Tel. 509-624-4276; Fax 509-838-3424)
11 Wells, St. John, Roberts, Gregory & Matkin P.S.
12 601 W. First Avenue, Suite 1300
13 Spokane, WA 99201-3828

13 Sir:

14 Responsive to the Office Action dated September 27, 2000,
15 applicant requests reconsideration of the above referenced application in
16 view of the amendments and remarks that follow [unless otherwise
17 indicated, deletions are bracketed, additions are underlined]:
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10/10
11-8-00
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